

Fig. 1

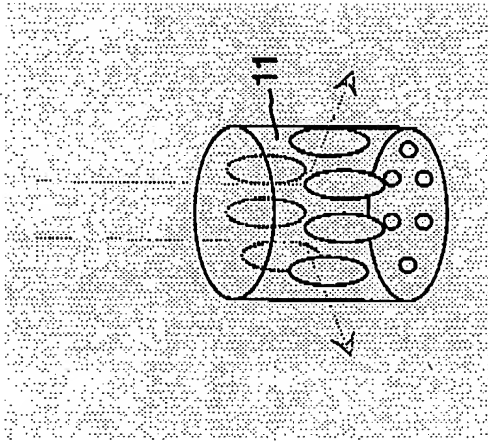
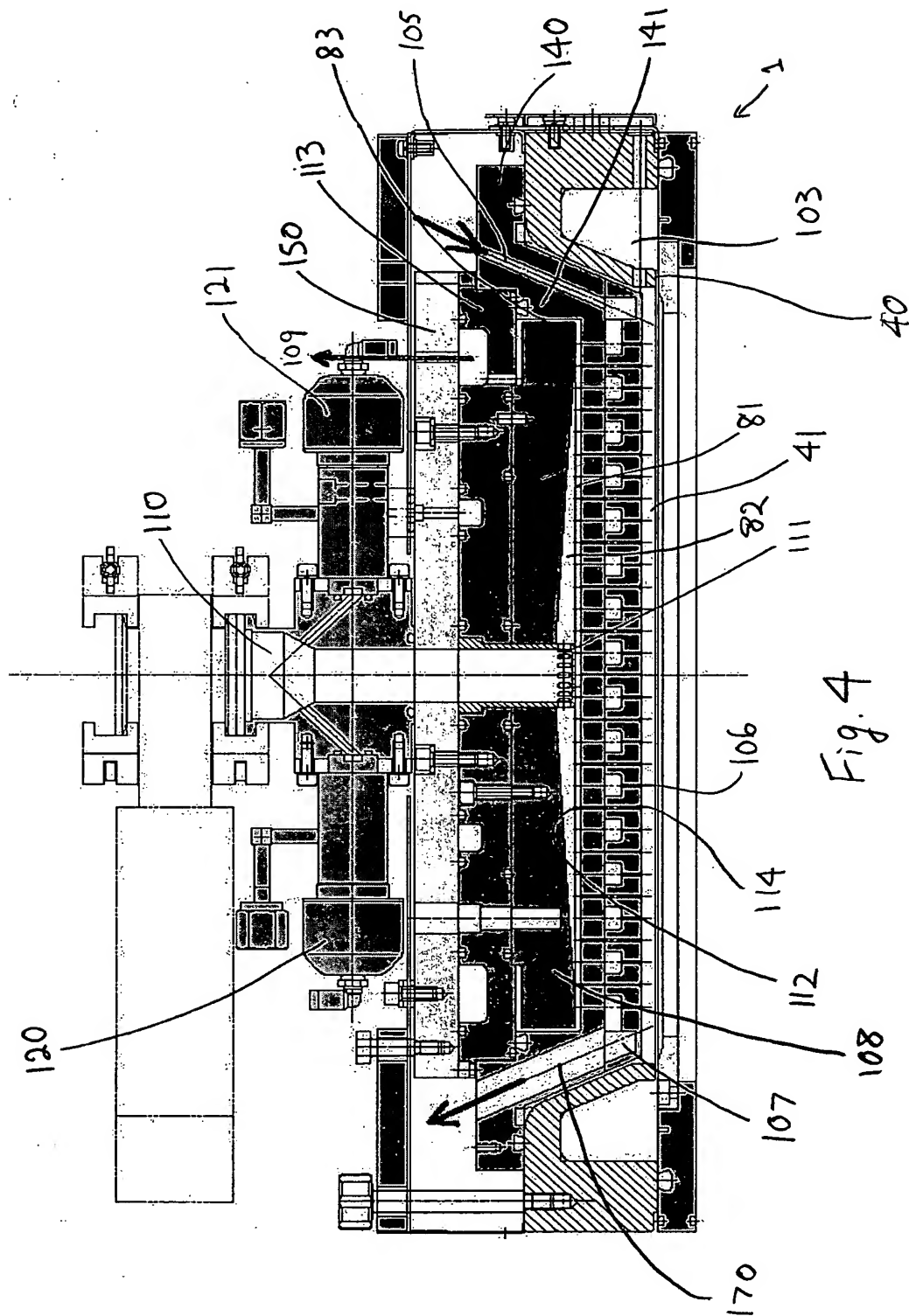


Fig. 2

	step1	step2	step3	step4	step5	step6	step7
Time	set time	set time	set time	set time	set time	set time	set time
gas valve	20 open	open	open	open	open	open	open
	21 close	open	close	close	close	close	close
	22 close	close	close	open	close	close	close
	23 open	open	open	open	open	open	open
	24 close	close	close	close	close	open	close
vacuum	25 open	open	open	open	open	open	open
exhaust	9 close	close	open	open	close	close	close
valve	32 close	close	close	close	close	close	open

Fig. 3



## Hiroshi SHINRIKI, et al.

Atty Docket: ASMJP.149AUS

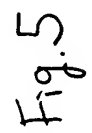


Fig. 5

	step1	step2	step3	step4	step5	step6	step7	step8	step9
Time	set time	set time	set time	set time	set time	set time	set time	set time	set time
gas valve	20 open	open	open	open	open	open	open	open	open
	21 close	open	close	close	close	close	close	close	close
	22 close	close	close	open	close	close	close	close	close
	23 open	open	open	open	open	open	open	open	open
	24 close	close	close	close	close	open	open	open	close
Plasma	off	off	off	off	off	off	on	off	off
vacuum	open	open	open	open	open	open	open	open	open
exhaust	close	close	open	open	close	close	close	close	close
valve	close	close	close	close	close	close	close	close	open

Fig.6

## Hiroshi SHINRIKI, et al.

Atty Docket: ASMJP.149AUS



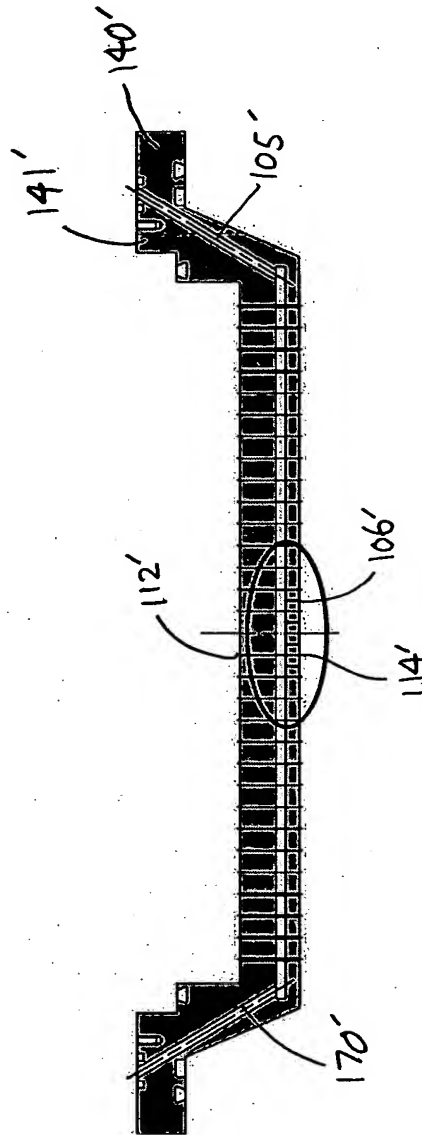


Fig. 8



### THIN-FILM DEPOSITION APPARATUS

Hiroshi SHINRIKI, et al.

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Atty Docket: ASMJP.149AUS

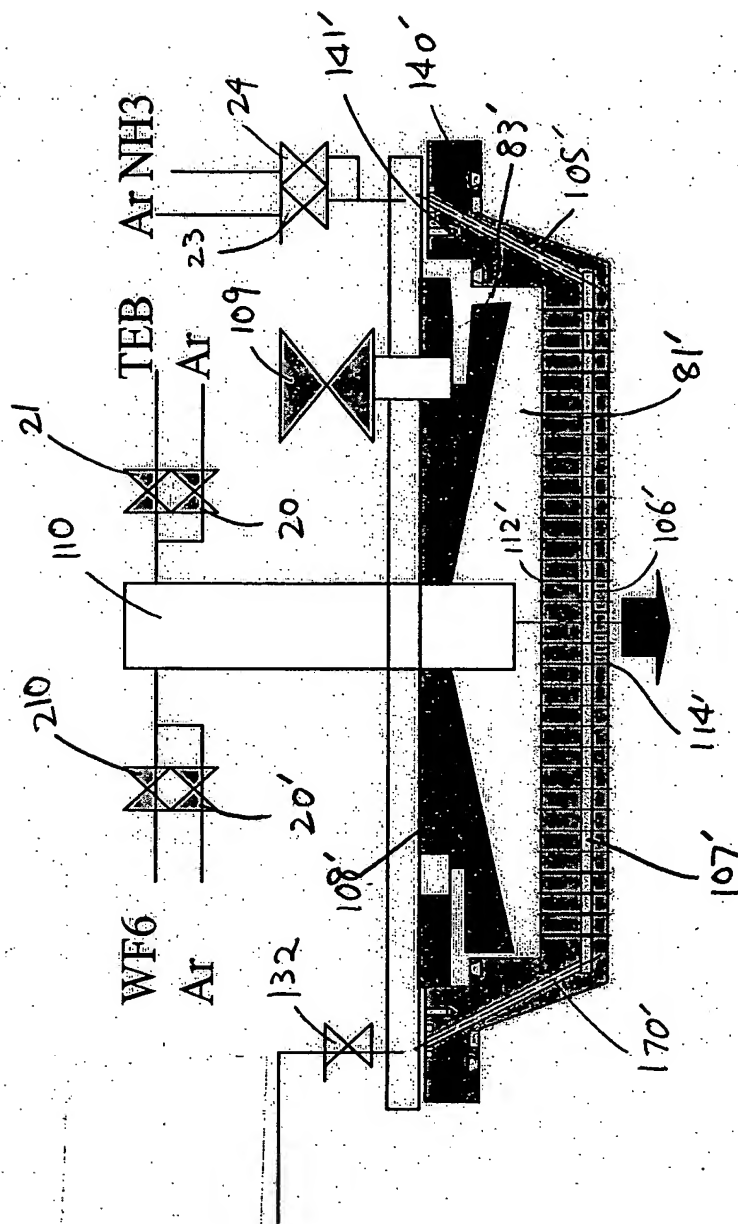


Fig. 9

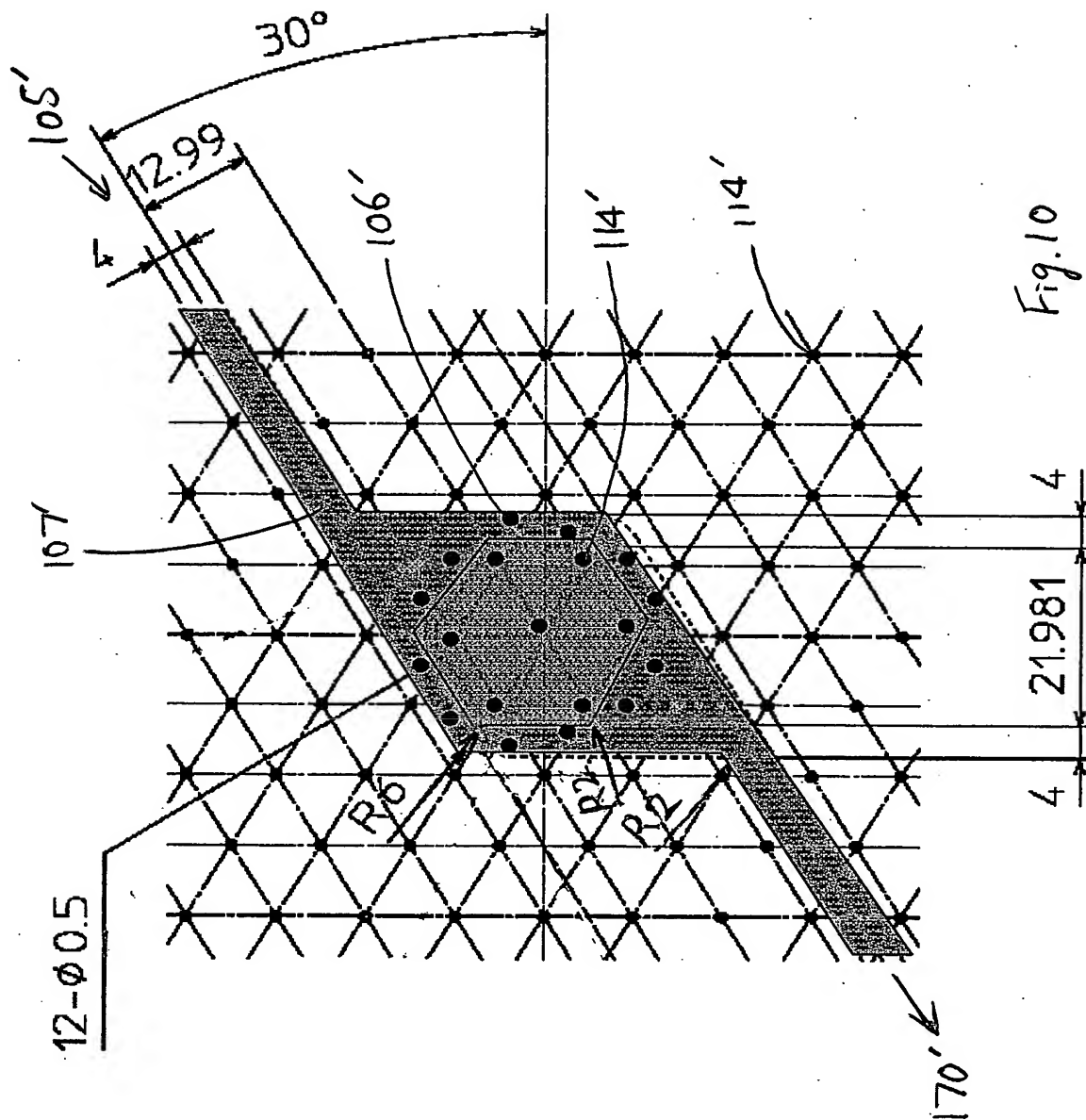


Fig. 10